

Notice of References Cited				Application/Control No.		Applicant(s)/Patent Under Reexamination	
				09/218,997		FUKAMI, TERUAKI	
				Examiner		Art Unit	
				Imad Soubra		1744	
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*		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	DOCUMENT SOURCE **	
							APS	OTHER
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<input type="checkbox"/>	B	5,466,389	Nov. 1995	Ilardi et al.	252	156	<input type="checkbox"/>	<input checked="" type="checkbox"/>
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*		DOCUMENT NO.	DATE	COUNTRY	NAME	CLASS	SUBCLASS	DOCUMENT SOURCE **	
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<input type="checkbox"/>	T							<input type="checkbox"/>	<input type="checkbox"/>

NON-PATENT DOCUMENTS				
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<input type="checkbox"/>	U	Kern, W., "Overview and Evolution of Semiconductor Wafer Contamination and Cleaning Technology", in Handbook of Semiconductor Wafer Cleaning Technology, Kern, W. (ed.), Noyes Publication, Parkridge, NJ, 1993.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
<input type="checkbox"/>	V		<input type="checkbox"/>	<input type="checkbox"/>
<input type="checkbox"/>	W		<input type="checkbox"/>	<input type="checkbox"/>
<input type="checkbox"/>	X		<input type="checkbox"/>	<input type="checkbox"/>

*A copy of this reference is not being furnished with this Office action. (See Manual of Patent Examining Procedure, Section 707.05(a).)

**APS encompasses any electronic search i.e. text, image, and Commercial Databases.

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PTO-892 (Rev. 03-98)

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Part of Paper No. 6